
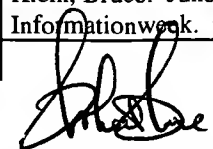


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|  | | | | APPLICANT Young Joseph PAIK | | | |
| | | | | FILING DATE November 30, 2001 | | GROUP 3723 | |
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INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(PTO-1449)



ATTY. DOCKET NO.
005917 USA/FET/FET

SERIAL NO.
09/998,372

APPLICANT
Young Joseph PAIK

FILING DATE
November 30, 2001

GROUP
3723

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